

Application No.: 10/607.814
Amendment dated January 31, 2005
Reply to Office Action of November 2, 2004

13. (original) The method of claim 12, wherein the act of providing an auxiliary electron-source surface includes providing a metallic surface that tracks a scanning beam around the target surface.

14. (original) The method of claim 8, wherein the act of irradiating the auxiliary electron source includes irradiating it with an ion beam.

15. (original) The method of claim 8, wherein the act of irradiating the auxiliary electron source includes irradiating it with an electron beam.

16- 26 (Cancelled)

27. (new) The method of claim 1 wherein the area of interest encompasses a feature to be cross-sectionally analyzed.

²⁸
28. (new) The method of claim 27, wherein the feature is a line feature disposed substantially along the center of a rectangular shaped target surface.

²⁹
29. (new) The method of claim 27, wherein the work piece is a wafer having a surface with a feature to be cross-sectionally analyzed, the act of identifying a target surface including defining a substantially rectangular shaped surface encompassing a portion of the feature to be analyzed.

³⁰ ²⁹
30. (new) The method of claim 29, wherein the act of defining an electron-source surface includes defining a surface that substantially surrounds the target surface.

³¹
31. (new) The method of claim 1, wherein the act of defining an electron-source surface includes defining a surface that substantially surrounds the target surface.

³²
32. (new) The method of claim 8 wherein the target surface encompasses a feature to be cross-sectionally analyzed.

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Rule 1.126
³³
~~34~~. (new) The method of claim ³²~~35~~, wherein the feature is a line feature disposed

substantially along the center of a rectangular shaped target surface.

Rule 1.126
³⁴
~~35~~. (new) The method of claim ³²~~35~~, wherein the work piece is a wafer having a surface

with a feature to be cross-sectionally analyzed, and the act of identifying a target surface

including defining a substantially rectangular shaped surface encompassing a portion of the

feature to be analyzed.

Rule 1.126
³⁵
~~36~~. (new) The method of claim ³⁴~~36~~, wherein the act of providing an auxiliary electron-

source surface includes providing a metallic surface that tracks a scanning beam around the

target surface.

Rule 1.126
³⁶
~~37~~. (new) The method of claim 8, wherein the act of defining an electron-source surface

includes defining a surface that substantially surrounds the target surface.